

Docket No. 240882US0

IN RE APPLICATION OF: Tomohisa KONNO, et al.

SERIAL NO: 10/626,521

FILED: July 25, 2003

FOR: AQUEOUS DISPERSION FOR CHEMICAL MECHANICAL POLISHING AND PRODUCTION PROCESS OF SEMICONDUCTOR DEVICE



JPW

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Transmitted herewith is an Amendment and Request for Reconsideration in the above-identified application.

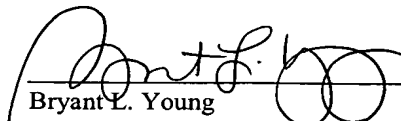
- ☒ No additional fee is required
- ☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- ☐ Additional documents filed herewith:

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	18	MINUS	20	0	x \$50 =	\$0.00
INDEPENDENT	2	MINUS	3	0	x \$200 =	\$0.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS			+ \$360 =	\$0.00
		TOTAL OF ABOVE CALCULATIONS				\$0.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment			+ \$40 =	\$0.00
		TOTAL				\$0.00

- ☐ A check in the amount of \$0.00 is attached.
- ☐ Credit card payment form is attached to cover the fees in the amount of \$0.00
- ☒ Please charge any additional Fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- ☒ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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DOCKET NO: 240882US0



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
TOMOHISA KONNO, ET AL. : EXAMINER: RACHUBA, MAURINA T.  
SERIAL NO: 10/626,521 :  
FILED: JULY 25, 2003 : GROUP ART UNIT: 3723  
FOR: AQUEOUS DISPERSION FOR :  
CHEMICAL MECHANICAL POLISHING  
AND PRODUCTION PROCESS OF  
SEMICONDUCTOR DEVICE

AMENDMENT AND REQUEST FOR RECONSIDERATION

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated September 30, 2005, Applicants respectfully request reconsideration of the above-identified application in view of the following amendments and remarks:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Support for the Amendment** begins on page 4 of this paper.

**Request for Reconsideration** begins on page 5 of this paper.